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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

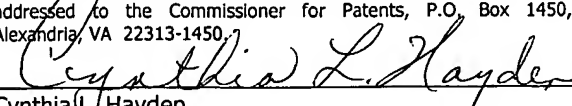
In re Applicant:	§	
Randy Skocypec et al.	§	Art Unit: 1746
	§	
Serial No.: 10/622,307	§	
	§	Examiner: Bibi Sharidan Carrillo
Filed: July 18, 2003	§	
	§	
For: Cleaning Semiconductor Wafers	§	Docket: ITL.1017US
	§	P16704
	§	

Mail Stop **Amendment**
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

REPLY TO PAPER NO. 09072004

Sir:

In response to the office action mailed September 9, 2004, please amend the above-referenced patent application as follows:

Date of Deposit: November 8, 2004
I hereby certify under 37 CFR 1.8(a) that this correspondence is being deposited with the United States Postal Service as **first class mail** with sufficient postage on the date indicated above and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Cynthia L. Hayden